

WP6: Novel high voltage and resistive CMOS sensors

*I. Peric (KIT), G. Casse (U. Liverpool),
P. Dervan (U. Liverpool) and S. Grinstein (IFAE-Barcelona)*



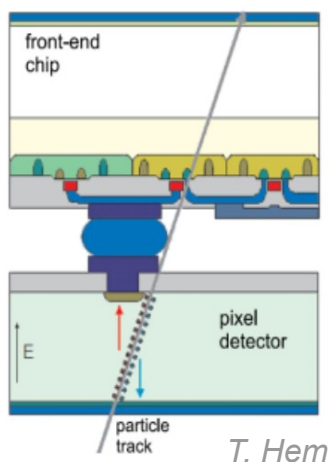
- Introduction to depleted CMOS devices
- Recapitulation of WP6 program and activities
- Early days: hybrid CMOS devices
- New path: Depleted Monolithic Active Pixel Sensors (DMAPS)
- From early prototypes to proven performance (selection of results*)
 - First HVCMOS devices: the challenge
 - Another approach: smaller electrodes
 - Beyond tracking
- Conclusions
- The future of DMAPS (AIDAInnova)

* Apologies if I missed your favourite result

** Note: slides summarize work done within AIDA (in particular included in AIDA publications, ie **not** a DMAPS review)

- Innermost layers of HEP accelerator-based experiments require:
 - **Position resolution**, radiation hardness, rate capability, compactness, low material budget...
- Technology of choice: **silicon pixel sensors**

Hybrid detectors



E.H.M. Heijne et al., NIM A 273 (1988) 615

Electronics
Interconnect
Sensor

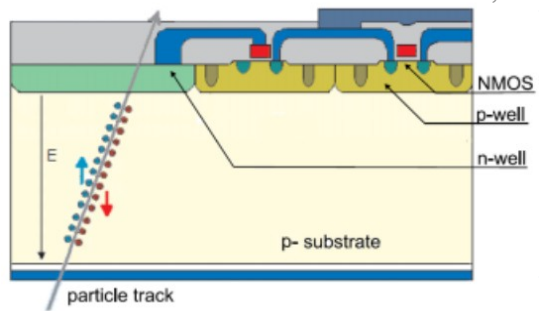
T. Hemperek, Bonn

- Standard in current experiments
- Design allows for optimization of electronics and sensor

Goal of WP6: Exploration of an innovative tracking-detector technology based on **depleted CMOS sensors**

I. Peric et al., NIM A 582 (2007) 876

Monolithic detectors



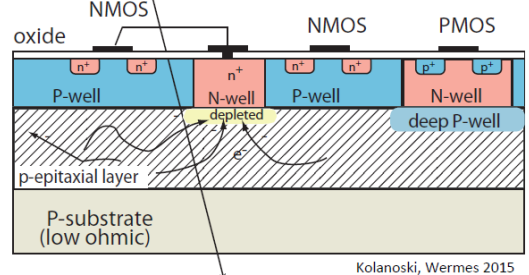
S. Parker, NIM A 275 (1989) 494

Electronics + sensor in same substrate

- Less material, less complexity
- Smaller pixel possible



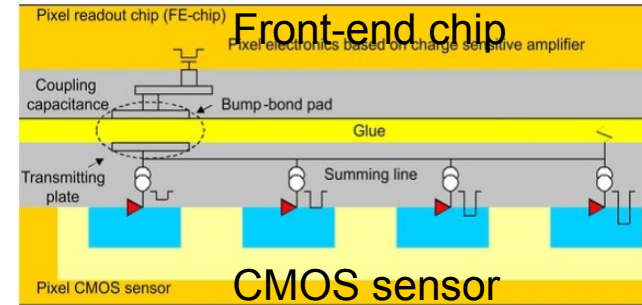
- Initially on ρ -low under-depleted bulk
- **MAPS: Monolithic Active Pixel Sensor**



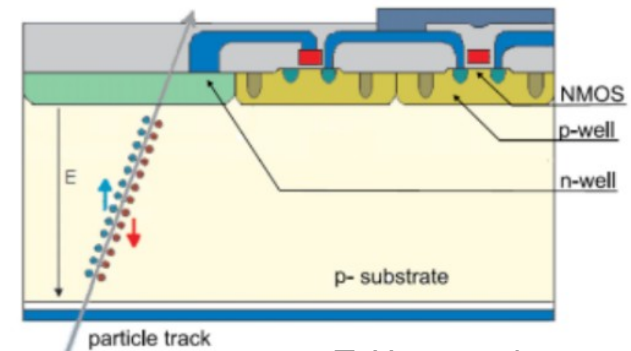
R. Turchetta et al. Sensors (2008)

Kolanoski, Wermes 2015

- **Goal of WP6:** Exploration of an innovative tracking-detector technology based on active CMOS sensors
- Initially, the focus of the activities were to investigate **AC coupled devices**
 - The reasons behind this approach:
 - AC coupling simpler (lower cost)
 - Full monolithic devices “too complicated”
 - (longer timescale)
- However, though hybrid CMOS devices were fabricated within the WP6 activities,
- In parallel, quick progress was made on **monolithic devices** (together with very encouraging results)
 - One substrate + no hybridization!
 - (less material, smaller pixels – no bumps,
 - lower cost)



I. Peric



T. Hemperek

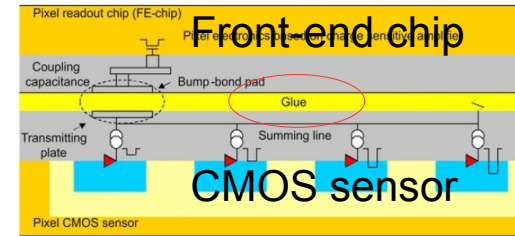
*Progress on DMAPS
main result of WP6*



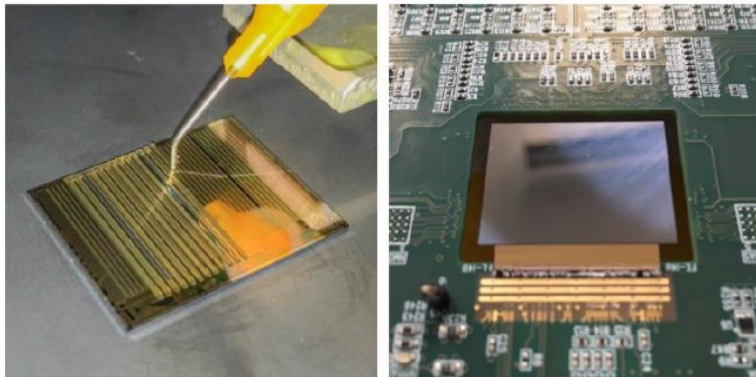
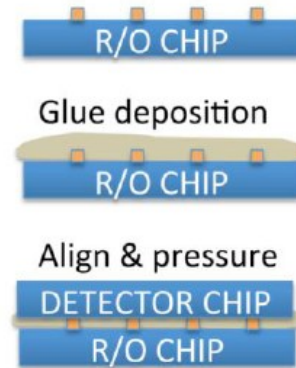
Task 6.3
Sensor development

• AC coupled devices

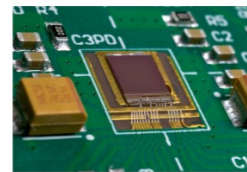
- “Simple” glue dispensing and “pick and place” procedure: not uniform couplings
- Improved approach with “pillars”
- Many prototypes produced and their performance
- before and after irradiation measured
 - 99.7% hit efficiency after 1E15 neq/cm2
 - However, fabrication process complicated
 - No advantage over standard hybrid devices



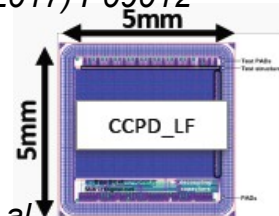
Pattern pillars by mask



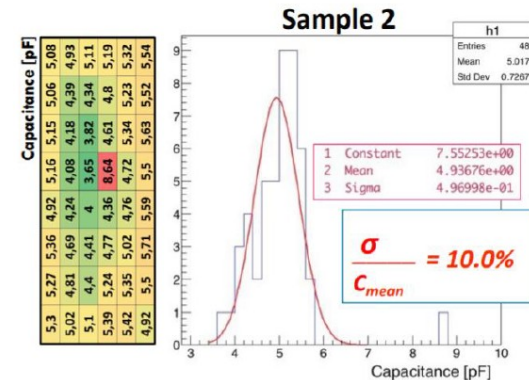
M. Benoit et al., JINST 13 (2018) P02011



I. Kremastiotis et al.,
JINST 12 (2017) P09012



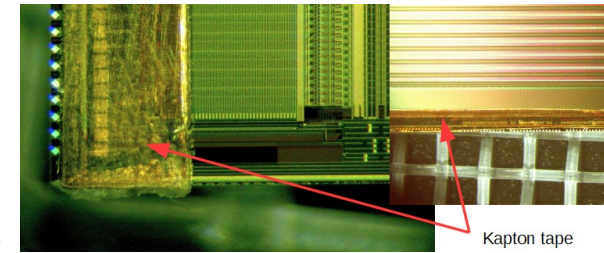
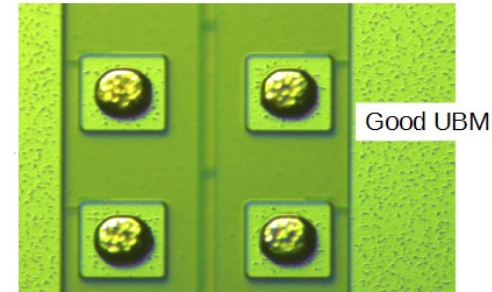
L. Vigani et al
2018 JINST 13 C02021



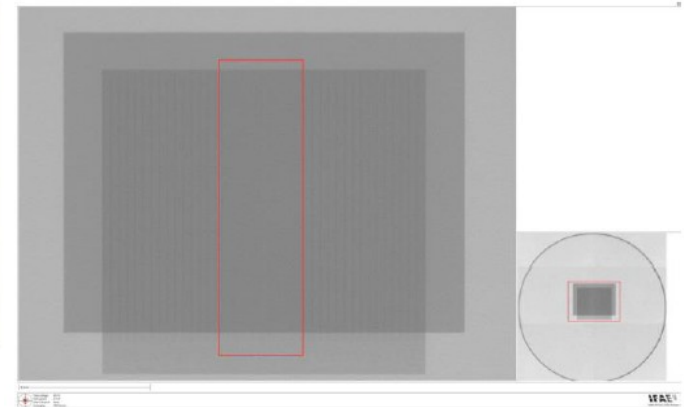
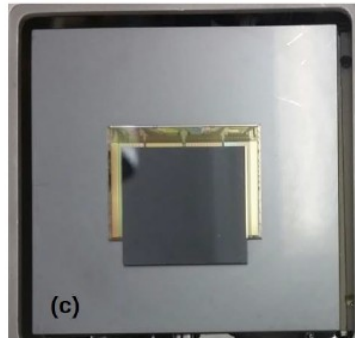
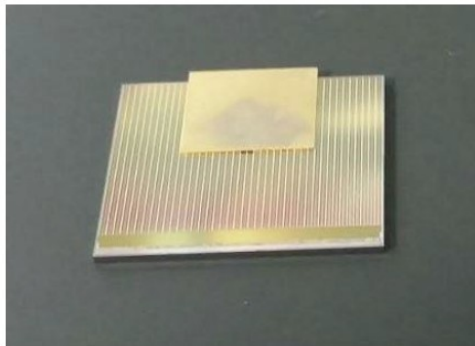
Difficult to achieve uniformity

- **AC/DC coupled devices**

- Combine DC and AC coupling to ensure
- uniformity
- Prototypes “investigators” produced
- Metalization of pads in single tiles (CMOS devices) needed
 - Protection of wire-bonding pads
- Selective removal of bumps in front-end (FEI4)
- Flip-chip process



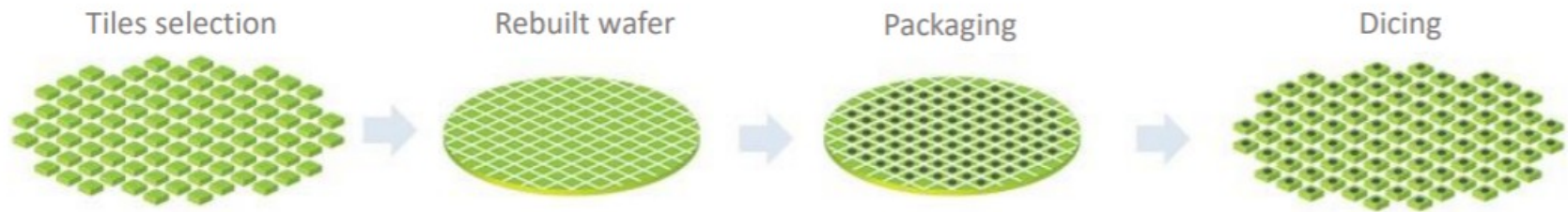
Several devices fabricated, but process complicated: no advantage over standard hybrid devices



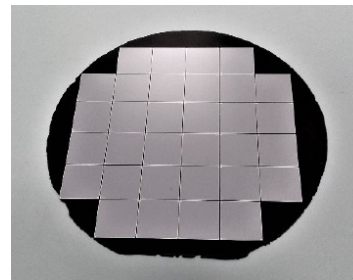
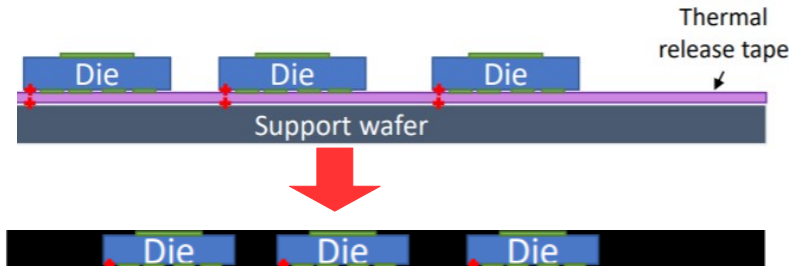
AIDA-2020-D6.6 report

- **Wafer Level Packaging (WLP)**

- One problem with CMOS hybrid devices is the fabrication of large sensors, due to reticle limit $\sim 4\text{cm}^2$ (stitching is one option)
- WLP allows to select good tiles and “reconstruct” wafer for further processing



- Technology also potentially promising for standard hybrid devices (with “low” yield technologies – eg 3D sensors)
 - Could avoid UBM process of bad sensors (cost saving)
- Tests showed that **bows about 100 μm** could be achieved, **but** position needed improvement for further photolithography steps



MicroFabSolutions

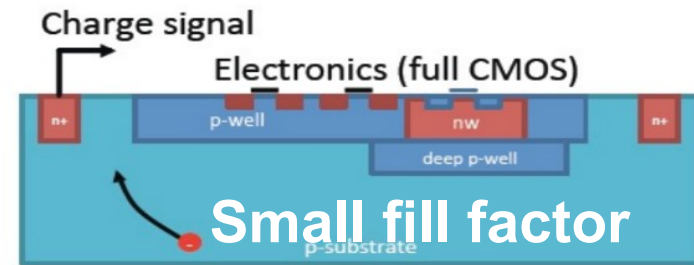
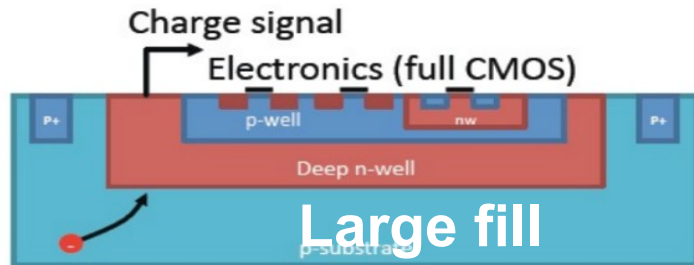
AIDA-2020-D6.7 report

- **HL-LHC is a harsh radiation environment** ($\sim 1E16 n_{eq}/cm^2$, 500 Mrad)
- For CMOS devices need higher radiation harness: **depleted substrates**
 - High voltage or high resistivity approach (HV/HR-CMOS)

$$d \sim \sqrt{\rho \cdot V}$$

I. Peric et al., NIM A 582 (2007) 876 (non-AIDA)

Two approaches to depleted-CMOS



- Electronics **inside** n-well
 - Full CMOS inside
 - Large collection node
 - Shorter drift distances (more rad hard)
- Electronics **outside** n-well
 - Full CMOS inside
 - Small collection node
 - Small capacitance (less noise & power)

Cons

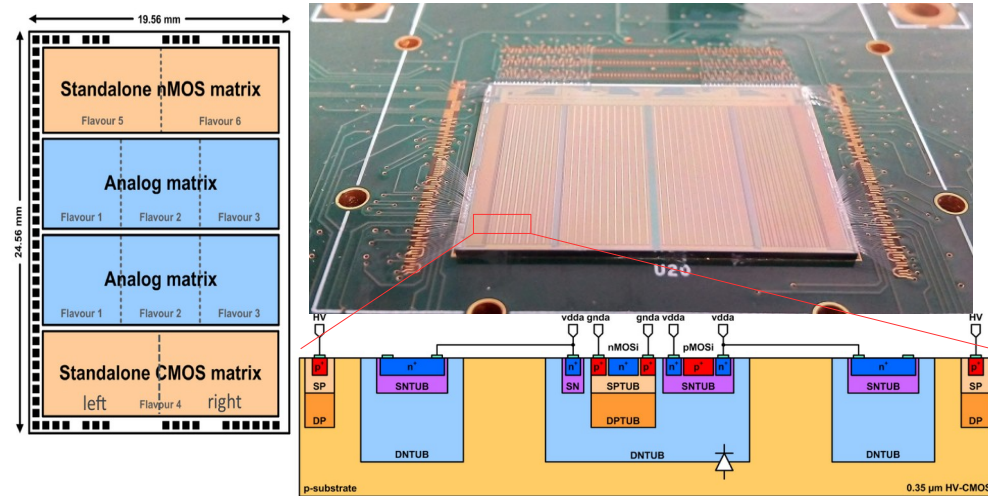
- Higher noise or power
- (larger capacitance)

Cons

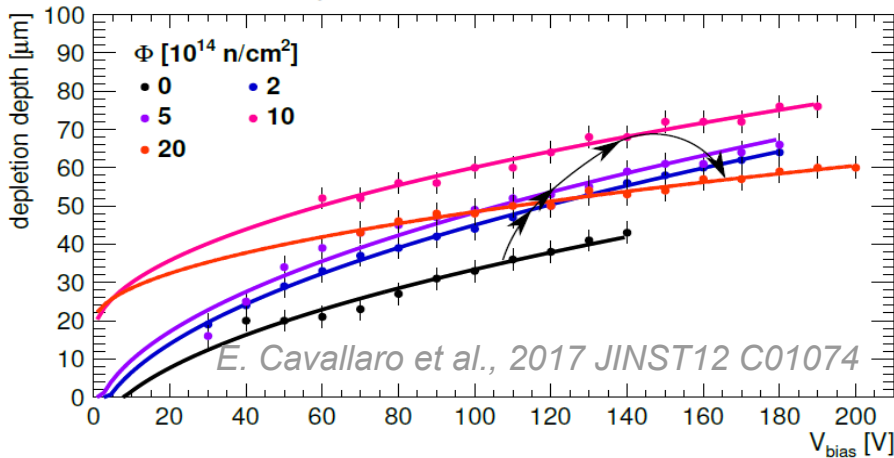
- Potential lower radiation hardness (larger drift)

H35demo: early full size ($\sim 2 \times 2 \text{ cm}^2$) investigator with large fill factor

- AMS 350 nm HV-CMOS
- $50 \times 250 \mu\text{m}^2$ pixels
- Two monolithic and two analog-only matrices (for AC coupling)
- Resistivity: 20-80-200-1000 Ωcm
- Pixel: CSA + Discr/2nd Ampl

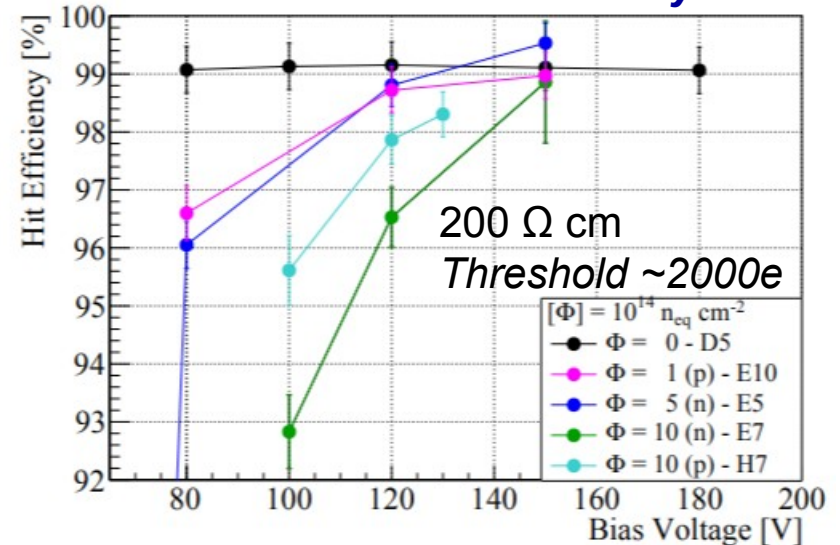


Sensor 2 - $\rho = 200 \Omega\text{ cm}$



- Good efficiency after $1 \text{ E}15 \text{ neq/cm}^2$
- **However**, 350 mW/cm^2

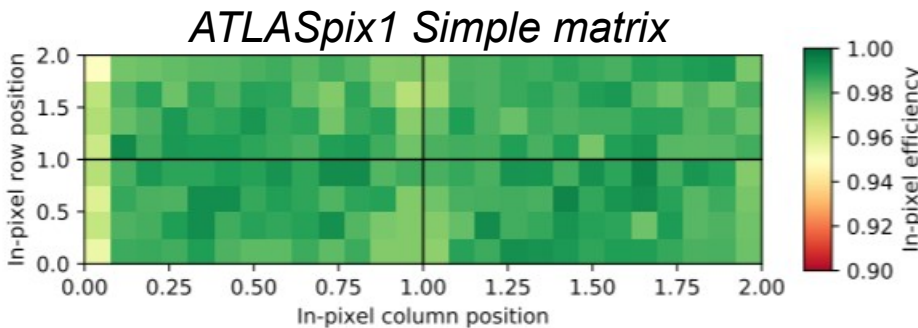
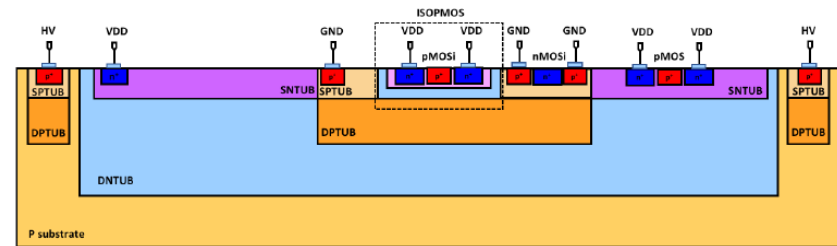
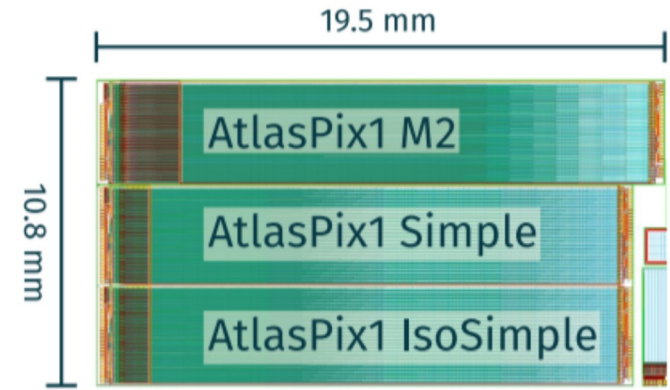
Hit reconstruction efficiency



S. Terzo et al 2019 JINST 14 P02016

ALTASpix1: large size prototype with large fill factor

- AMS 180 nm HV-CMOS process
- $130 \times 40 \mu\text{m}^2$ (M2: $60 \times 50 \mu\text{m}^2$) pixels
- Three flavours: simple (nMOS transistors), IsoSimple (CMOS) and M2 (triggered readout)
- Similar to column-drain readout
- Resistivity: 20-80-200-1000 Ωcm



99.5% after $1\text{E}15 \text{ neq/cm}^2$ (n)

F. Ehrlert et al., NIM A 936 (2019) 654-656

M. Kiehn et al 2019 JINST 14 C08013 (non-AIDA)

- Very good results after irradiation
 - At 80V and threshold $\sim 1000e$
 - Up to **$2\text{E}15 \text{ neq/cm}^2$** (n)
- Power dissipation $< 150 \text{ mW/cm}^2$



ATLASpix3:

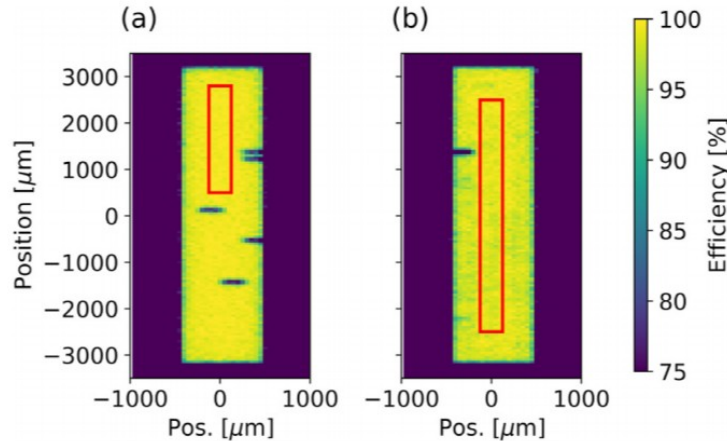
- TSI 180 nm
- $50 \times 150 \mu\text{m}^2$ pixels
- Compatible with RD53 readout

R. Schimassek et al, TWEPP 2019

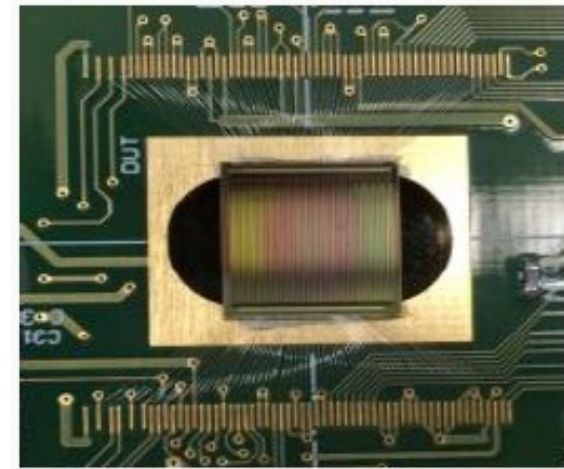
LF-Monopix: large size prototype with large fill factor

- LFoundry 150 nm process
- $50 \times 250 \mu\text{m}^2$ pixels
- Resistivity $> 2000 \Omega\text{cm}$
- Thickness: 750, 200, 100 μm
 - Backside processing for full depletion
- Column-drain readout

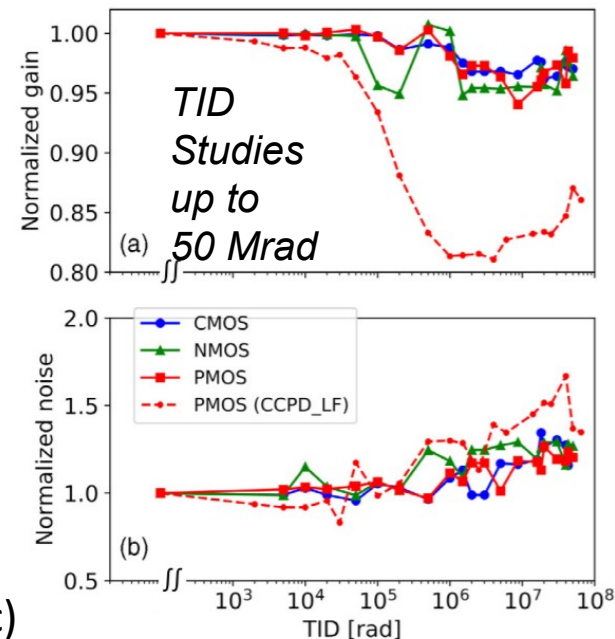
T. Hirono et al., NIMA 924 (2019) 87



- Results at 130 V and 1700 e threshold
- 98.9% hit reconstruction efficiency ($1\text{E}15 \text{ neq}/\text{cm}^2$)
- LFMonopix2 ($50 \times 150 \mu\text{m}^2$) recently submitted (tbc)

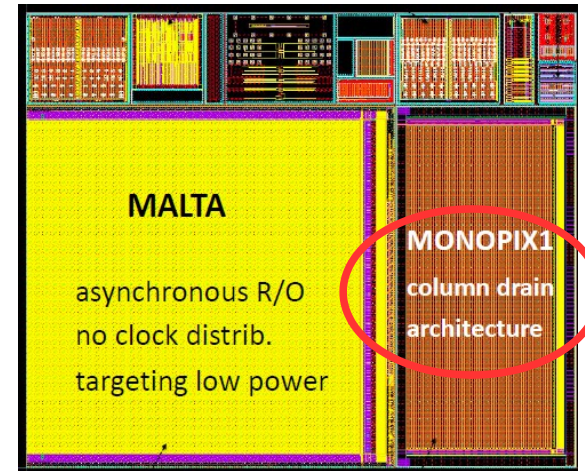


10 mm x 10 mm

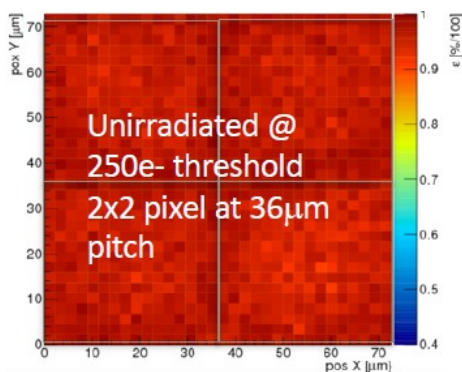


TJ-Monopix: small electrode prototype

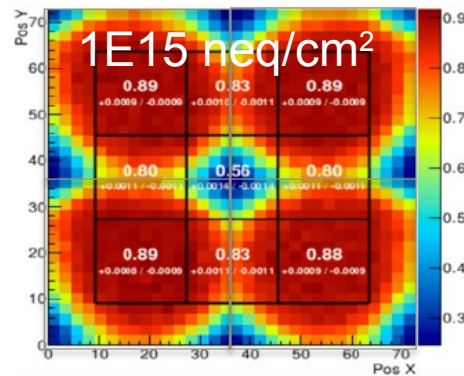
- TowerJazz 180 nm CMOS CIS
- Full CMOS in pixel
- $36 \times 40 \mu\text{m}^2$ pixels
- Epi thickness: 20 – 30 μm
- Resistivity: 1 k Ω cm
- **Modified process** to improve lateral depletion
 - See next slide



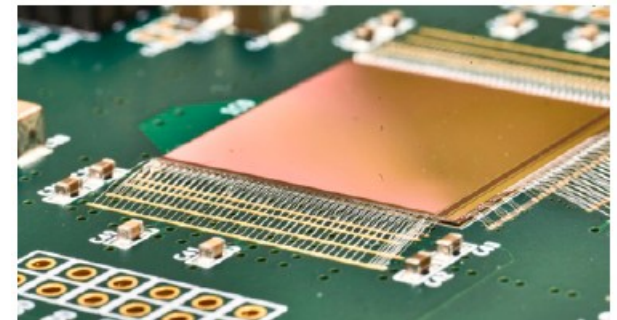
8 mm x 18 mm



350e threshold



570e threshold

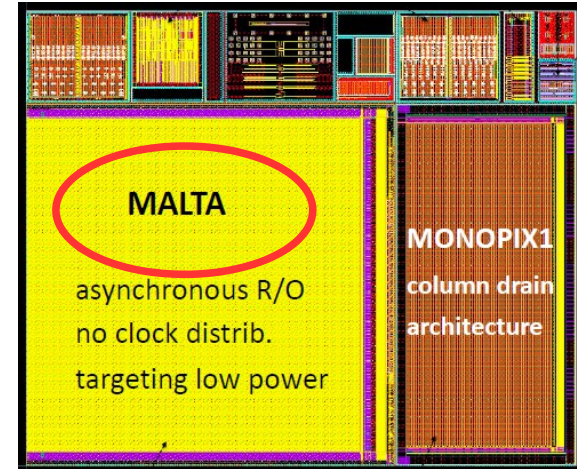


I. Caicedo et al., JINST 14 (2019) C06006
N. Wemes, CERN Seminar 2020

- Low threshold, low noise and low power dissipation (3 μW /pixel)...
- Irradiation results (to 1E15neq/cm²) showed some loss of efficiency in corners
 - Add p-implant to improve transverse E field, higher resistive substrates,... (TJ-Monopix2, MALTA next slides)

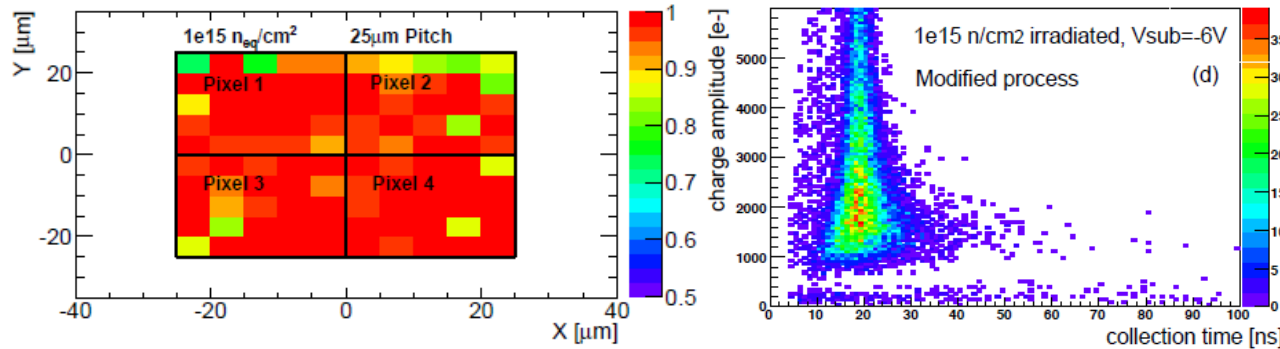
MALTA

- TowerJazz 180 nm CMOS CIS
- Full CMOS in pixel
- 25 x 25 μm^2 (and other sizes) pixels
- Epi thickness: 20 – 30 μm
- High resistivity: 1-8 $\text{k}\Omega \text{ cm}$
- **Modified process*** to improve lateral depletion
 - Derived from ALICE development (CERN)



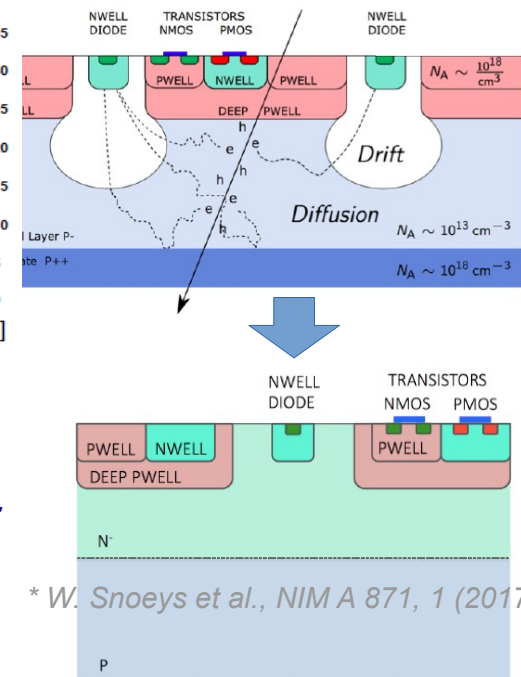
H. Pernegger et al 2017 JINST 12 P06008

16 mm x 18 mm



98.5% efficiency after 1E15 neq/cm2 & Fast charge collection

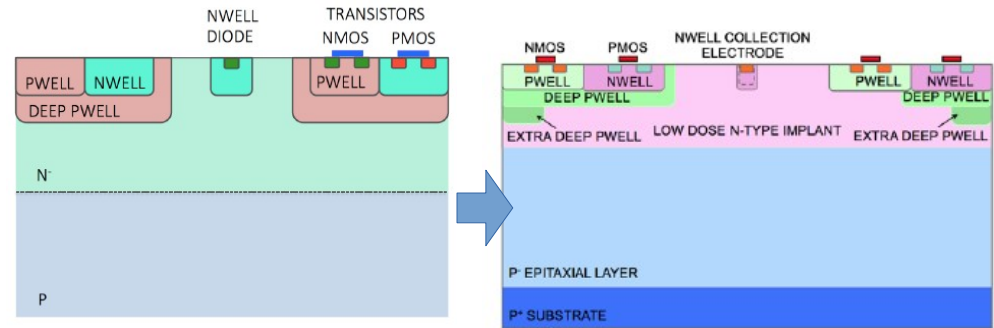
- Very good results after irradiation with modified process
 - *Applies also to TJ-Monopix, devices on same wafer and same sensor design!*
- Further optimization being investigated (next slide)



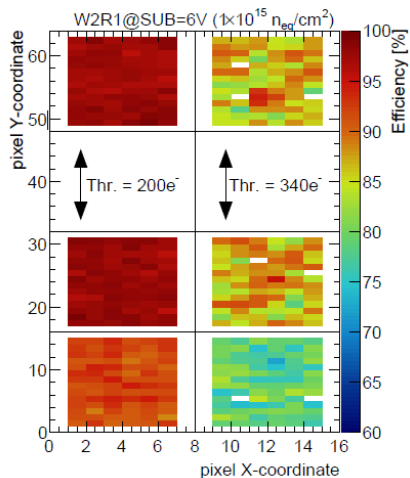
* W. Snoeys et al., NIM A 871, 1 (2017) 90

Mini-MALTA

- TowerJazz 180 nm CMOS CIS
- Full CMOS in pixel
- $36.4 \times 36.4 \mu\text{m}^2$ pixels
- Epi thickness: 20 – 30 μm
- High resistivity: 1 k Ω cm
- **Modified process*** to improve lateral depletion
- TCAD simulations used to optimize sensor design
 - *Simulations used in general as a*
 - *tool to aid design (AIDA-2020-D6.1)*



Improve E field in corners



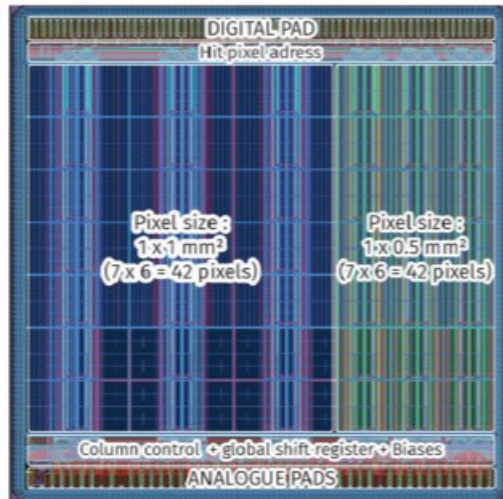
- Many options tested
- Very good results up to $1\text{E}15\text{neq}/\text{cm}^2$

Table 2. Summary of the efficiency measurements for various Mini-MALTA chips. The values are shown separately for different sensor regions. All chips were operated at low threshold settings. The uncertainties listed are statistical.

Chip ID	EPI [μm]	Fluence [$1 \text{ MeV neq}/\text{cm}^2$]	SUB [V]	Process modification	Efficiency (enlarged trans. region) [%] / threshold [e^-]	Efficiency (standard trans. region) [%] / threshold [e^-]
W2R11	30	unirrad.	-6	n ⁻ gap	$99.6 \pm 0.1 / 200e^-$	$99.1 \pm 0.1 / 380e^-$
				extra deep p-well	$99.6 \pm 0.1 / 200e^-$	$98.9 \pm 0.1 / 380e^-$
				continuous n ⁻	$99.6 \pm 0.1 / 200e^-$	$97.9 \pm 0.1 / 380e^-$
W2R1	30	1×10^{15}	-6	n ⁻ gap	$97.6 \pm 0.1 / 105e^-$	$86.5 \pm 0.1 / 210e^-$
				extra deep p-well	$97.9 \pm 0.1 / 105e^-$	$87.0 \pm 0.1 / 210e^-$
				continuous n ⁻	$91.9 \pm 0.1 / 105e^-$	$78.8 \pm 0.2 / 210e^-$
W4R2	25	1×10^{15}	-6	n ⁻ gap	$98.8 \pm 0.1 / 120e^-$	$90.7 \pm 0.1 / 275e^-$
				extra deep p-well	$99.2 \pm 0.1 / 120e^-$	$92.5 \pm 0.1 / 275e^-$
				continuous n ⁻	$95.8 \pm 0.1 / 120e^-$	$79.4 \pm 0.2 / 275e^-$
W5R3	25	2×10^{15}	-10	n ⁻ gap	$92.1 \pm 0.2 / 120e^-$	$73.1 \pm 0.3 / 230e^-$
				extra deep p-well	$93.7 \pm 0.2 / 120e^-$	$76.4 \pm 0.3 / 230e^-$
				continuous n ⁻	$86.5 \pm 0.2 / 120e^-$	$70.9 \pm 0.3 / 230e^-$

CACTUS (CMOS Active Timing μ Sensor)

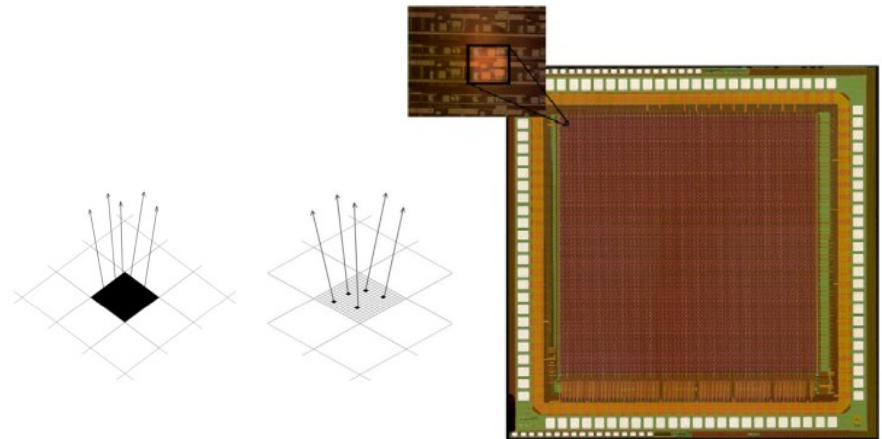
- Timing in a depleted CMOS device for pile-up rejection
- Target 50-80 ps/mip
- First investigator in LF 150 nm technology



F. Guilloux et al., PoS (TWEPP-17) 024

DECAL (digital electromagnetic calorimeter)

- Reconfigurable depleted MAPS sensor for digital electromagnetic calorimetry
- Improve E resolution by measuring number of particles in calorimeter shower



*P. Allport et al.,
NIMA 958 (2020) 162654*

- WP6 target was to investigate HV/HR CMOS devices for tracking in HEP
- Early on, **depleted monolithic devices** identified as the most promising approach
 - However, big effort on AC coupled devices w/ many lessons learned
- Two approaches pursued on DMAPS: large and small electrodes
 - Both produced very promising results, demonstrating that DMAPS are a leading option for *moderate* radiation hardness requirements
 - Large electrode probably best suited for radiation hardness
 - Small electrode best if low power dissipation critical
- The potential of/interest in the technology reflected in about **30** publications within AIDA2020 (and many more non-AIDA)

Thanks to all the groups that made such a big progress on DMAPS

- However technology a bit late (system aspects) for LS3 upgrades
 - But huge advancement, can not be ignored, even by the most conservative researchers...
- DMAPS are becoming option/baseline for future experiments
 - CEPC (investigating TJ 180nm), ILC, LS4 upgrades...
- **AIDAInnova** aim to continue playing critical role in pre-TDR projects
- Proposed physics oriented WP structure:
 - High granularity and low mass devices:
Higgs factories, ALICE, Belle
 - Radiation hard and fast devices
LS4 upgrades of ATLAS/CMS, LHCb

**Thanks to all the groups that made such a big progress on DMAPS
and looking forward to continue the activities within AIDAInnova**

Back Up Slides

Deliverables

Del. no.	Deliverable name	WP no.	Planned delivery date	Actual delivery date	Status	Comments
D6.5	Optimised interconnection process	6	M42	13/05/2019	Achieved	Report Justification for delay
D6.6	Assemblies delivered	6	M40	31/08/2018	Achieved	Report
D6.1	TCAD libraries	6	M40	30/09/2018	Achieved	Report
D6.2	Sensor-design guidelines	6	M46	02/04/2019	Achieved	Report
D6.7	Recommendation for industrialisation	6	M46	22/03/2019	Achieved	Report
D6.3	Performance characterisation results	6	M58	20/04/2020	Achieved	Report
D6.4	Radiation tolerance assessment	6	M58	25/03/2020	Achieved	Report
D6.8	Final report on HV/ HR CMOS devices	6	M58	20/04/2020	Achieved	Report

Milestones

Mil. no.	Milestone name	WP no.	Planned delivery date	Actual delivery date	Status	Comments
MS7	Simulation workshop on HV/HR-CMOS TCAD and Geant4 simulations	6	M6	26/05/2016	Achieved	Justification for delay Report
MS11	MPWR submission	6	M12	03/06/2016	Achieved	Report
MS26	First test beam campaign with initial sensor prototype assemblies	6	M16	21/12/2016	Achieved	Report
MS27	First irradiation campaign with sensor prototype assemblies	6	M16	21/12/2016	Achieved	Report
MS28	First functional HV/HR-CMOS assembly with capacitive interconnection	6	M16	30/09/2016	Achieved	Report
MS48	Simulation tutorial on HV/HRCMOS TCAD and Geant4 simulations	6	M24	28/04/2017	Achieved	Report